

<b>Notice of References Cited</b>	Application/Control No. 10/720,838		Applicant(s)/Patent Under Reexamination GROS-JEAN ET AL.	
	Examiner B. Chen		Art Unit 1762	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,784,049 B2	08-2004	Vaartstra, Brian A.	438/240
*	B	US-6,787,186 B1	09-2004	Hintermaier, Frank S.	427/255.31
*	C	US-6,616,972 B1	09-2003	Senzaki et al.	427/255.31
*	D	US-2005/0163659 A1	07-2005	Duveneck et al.	422/061
*	E	US-6,806,210 B2	10-2004	Shiho et al.	438/785
*	F	US-5,271,957 A	12-1993	Wernberg et al.	427/109
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Chiu, H.T., et al.; Metal-Organic CVD of Tantalum Oxide from tert-Butylimidotris(diethylamido)tantalum and Oxygen. Chemical Vapor Deposition, Vol.6, Issue 5, pp.223-225. October 2000. ABSTRACT AND REFERENCE UNAVAILABLE.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.